

Notice of References Cited		Application/Control No.	Applicant(s)/Patent Under Reexamination SPIEGELMAN ET AL.	
		Examiner Sharidan Carrillo	Art Unit 1746	Page 1 of 1

U.S. PATENT DOCUMENTS

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
A	US-5,351,415	10-1994	Brooks et al.	34/389
B	US-5,602,683	02-1997	Straaijer et al.	359/811
C	US-5,846,338	12-1998	Bonora et al.	134/11
D	US-5,869,401	02-1999	Brunemeier et al.	438/710
E	US-6,391,090	05-2002	Alvarez et al.	95/116
F	US-6,427,703	08-2002	Somekh, Sasson	134/1.1
G	US-6,638,341	10-2003	Spiegelman et al.	95/104
H	US-6,724,460	04-2004	Van Schaik et al.	355/30
I	US-2002/0192129	12-2002	Shamoulian et al.	422/177
J	US-2002/0018189	02-2002	Mulkens et al.	355/30
K	US-2003/0096193	05-2003	Van Schaik et al.	430/296
L	US-			
M	US-			

FOREIGN PATENT DOCUMENTS

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
N					
O					
P					
Q					
R					
S					
T					

NON-PATENT DOCUMENTS

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)	
U	Kern, Werner; "Handbook of Semiconductor Wafer Cleaning Technology", 1993, pages 88-89	
V		
W		
X		

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.